

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	233815	("73").CLAS.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	OFF	2008/01/06 10:20
L2	2694	1 and gas adj (sensor transducer) and (sensor transducer) adj element and contact adj pad semiconductor adj film and substrate and (heater heat\$3 adj element)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 10:27
L3	1279	2 and gas adj (sensor transducer) and (sensor transducer) adj element and contact adj pad semiconductor adj film and insulat\$3 near3 substrate and (heater heat\$3 adj element)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 10:27
L4	6034	1 and gas adj (sensor transducer) and (sensor transducer) adj element and contact adj pad semiconductor adj (layer film) and substrate and (heater heat\$3 adj element)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 10:27
L5	2379	4 and gas adj (sensor transducer) and (sensor transducer) adj element and contact adj pad semiconductor adj (layer film) and insulat\$3 near3 substrate and (heater heat\$3 adj element)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 10:28
L6	558	4 and gas adj (sensor transducer) and (sensor transducer) adj element and contact adj pad semiconductor adj (layer film) same (metal adj oxide tin zinc iron "Tn" "Zn" "Fe") and insulat\$3 near3 substrate and (heater heat\$3 adj element)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 13:35
L7	582	4 and gas adj (sensor transducer) and (sensor transducer) adj element and contact adj pad semiconductor adj (layer film) same (metal adj oxide tin zinc iron "Sn" "Zn" "Fe") and insulat\$3 near3 substrate and (heater heat\$3 adj element)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 13:30
L8	565	(73/31.06).CCLS.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	OFF	2008/01/06 11:15

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L9	545	8 not 7	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 11:15
L10	600	fluid adj (sensor transducer) and (sensor transducer) adj element and contact adj pad semiconductor adj (layer film) same (metal adj oxide tin zinc iron "Sn" "Zn" "Fe") and insulat\$3 near3 substrate and (heater heat\$3 adj element)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 12:13
L11	581	1 and fluid adj (sensor transducer) and (sensor transducer) adj element and contact adj pad semiconductor adj (layer film) same (metal adj oxide tin zinc iron "Sn" "Zn" "Fe") and insulat\$3 near3 substrate and (heater heat\$3 adj element)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 12:08
L12	52	11 not 6	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 12:08
L13	540	10 not 1	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 12:13
L14	655	gas adj (sensor transducer) and (sensor transducer) adj element and contact adj pad semiconductor adj (layer film) same (metal adj oxide tin zinc iron "Sn" "Zn" "Fe") and insulat\$3 near3 substrate and (heater heat\$3 adj element) not 1	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 12:14
L15	1	14 and (semiconductor adj (layer film) same (metal adj oxide tin zinc iron "Sn" "Zn" "Fe") and insulat\$3 near3 substrate and (heater heat\$3 adj element)) same ("same" adj (side surface))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 12:18
L16	1	6 and (semiconductor adj (layer film) same (metal adj oxide tin zinc iron "Sn" "Zn" "Fe") and insulat\$3 near3 substrate and (heater heat\$3 adj element)) same ("same" adj (side surface))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 12:19

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L17	4	US-4338281-\$.DID. OR US-4389373-\$.DID. OR US-4457161-\$.DID. OR US-5367283-\$.DID.	US-PGPUB; USPAT; USOCR	OR	ON	2008/01/06 13:05
L18	6	("5837886").URPN.	USPAT	OR	ON	2008/01/06 13:10
L19	19	("3676820" "3906473" "4221827" "4224280" "4237722" "4396899" "4399424" "4399684" "4580439" "4596975" "4816800" "4938928" "4967589" "4984446" "5012671" "5389225" "5400643" "5455390" "5466605").PN.	US-PGPUB; USPAT; USOCR	OR	ON	2008/01/06 13:11
L20	38	(US-20040211667-\$ or US-20040147137-\$ or US-20040099047-\$ or US-20030230749-\$ or US-20030233864-\$).did. or (US-7230316-\$ or US-7105392-\$ or US-6786076-\$ or US-5837886-\$ or US-5783153-\$ or US-5759367-\$ or US-5457333-\$ or US-5019885-\$ or US-4977658-\$ or US-4911892-\$ or US-4885929-\$ or US-4740387-\$ or US-4673910-\$ or US-4621249-\$ or US-4453151-\$ or US-4169369-\$ or US-6109095-\$ or US-6012327-\$ or US-5918261-\$ or US-5012671-\$ or US-5003812-\$ or US-4991424-\$ or US-4984446-\$ or US-4457161-\$ or US-4938928-\$ or US-4816800-\$). did. or (US-4580439-\$ or US-4399424-\$).did. or (US-3503030-\$).did. or (JP-63231254-\$ or JP-04164243-\$ or JP-04348267-\$).did. or (DE-2942516-\$).did.	US-PGPUB; USPAT; USOCR; JPO; DERWENT	OR	ON	2008/01/06 13:30
L21	546	20 and (sensor measuring sensing transducer) adj element and contact adj pad semiconductor adj (layer film) same (metal adj oxide tin zinc iron "Sn" "Zn" "Fe") and insulat\$3 near3 substrate and (heater heat\$3 adj element)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 13:34
L22	546	L20 and (sensor measuring sensing transducer) adj element and contact adj pad semiconductor adj (layer film) same (metal adj oxide tin zinc iron "Sn" "Zn" "Fe") and insulat\$3 near3 substrate and (heater heat\$3 adj element)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 13:34

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L23	92	L20 and gas adj (sensor transducer) and (sensor measuring sensing transducer) adj element and contact adj pad semiconductor adj (layer film) same (metal adj oxide tin zinc iron "Tn" "Zn" "Fe") and insulat\$3 near3 substrate and (heater heat\$3) adj element	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 13:47
L24	35	L20 and (alumina aluminum aluminum with compound "Al")	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 14:18
L25	26	L20 and (silicon "Si")	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 14:18
L26	29	L20 and (silicon silica "Si")	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 15:52
L27	13	L20 and surface adj area	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 15:00
L28	4	L20 and serpentine	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 15:49
L29	4	L20 and (insultating insulation) with (layer lamina film) same substrate	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 15:49
L30	24	L20 and (silicon silica "Si") with substrate	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 15:57
L31	16	L20 and (silicon silica "Si") with substrate same (insulating insulation) with (layer lamina film)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 16:15

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L32	7	L20 and (contact pad electrode connect\$3) same (("Ti" titanium) and ("Pt" platinum))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 16:17
L33	37	20 not 17	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2008/01/06 16:37
S1	5	"830133".ap.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	ON	2007/08/10 14:11
S2	4	US-4338281-\$.DID. OR US-4389373-\$.DID. OR US-4457161-\$.DID. OR US-5367283-\$.DID.	US-PGPUB; USPAT; USOCR	OR	ON	2008/01/06 10:18